

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:)
Yeong-Kwan KIM, et al.)
Serial No. 09/902,607)
Filed: July 12, 2001)
For: Semiconductor Device Having)
Thin Film Formed by Atomic)
Layer Deposition and Method)
for Fabricating the Same)

)
Examiner: Toniae M. Thomas
Art Unit: 2822
Atty. Docket No.: 249/258

A9
Response
(supl)

SUPPLEMENTAL AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents
United States Patent and Trademark Office
Washington, D.C. 20231

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OFFICE OF PETITIONS

Sir:

Pursuant to the Amendment filed on February 7, 2003, attached hereto is the Certified English Translation of the Korean Priority Document.

Respectfully submitted,

Date: February 11, 2003


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PETITION and
DEPOSIT ACCOUNT CHARGE AUTHORIZATION

This document and any concurrently filed papers are believed to be timely. Should any extension of the term be required, applicant hereby petitions the Director for such extension and requests that any applicable petition fee be charged to Deposit Account No. 50-1645.

If fee payment is enclosed, this amount is believed to be correct. However, the Director is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-1645.

Any additional fee(s) necessary to effect the proper and timely filing of the accompanying-papers may also be charged to Deposit Account No. 50-1645.